

## Scalable high-mobility graphene/hBN heterostructure

**Leonardo Martini<sup>1</sup>, Vaidotas Miseikis<sup>1,2</sup>, David Esteban<sup>3</sup>, Jon Azpeitia<sup>3</sup>, Sergio Pezzini<sup>4</sup>,  
 Paolo Paletti<sup>1,2</sup>, Domenica Convertino<sup>1,2</sup>, Ignacio Jimenez<sup>3</sup>, Camilla Coletti<sup>1,2</sup>**

1. Center for Nanotechnology Innovation @ NEST, Istituto Italiano di Tecnologia, Piazza San Silvestro 12, 56127, Pisa, Italy
2. Graphene Labs, Istituto italiano di tecnologia, Via Morego 30, I-16163 Genova, Italy
3. Instituto de Ciencia de Materiales de Madrid, Consejo Superior de Investigaciones Científicas, E-28049 Madrid, Spain
4. NEST, Istituto Nanoscienze-CNR and Scuola Normale Superiore, Piazza San Silvestro 12, 56127, Pisa, Italy

leonardo.martini@iit.it

The high-mobility of graphene can be exploited in several applications, from high-frequency electronics to photonics and opto-electronics[1]. Chemical vapour deposition (CVD)-grown graphene has proved to perform in pair with the highest quality exfoliated flakes, when integrated into heterostructures with hexagonal Boron Nitride(h-BN)[2]. In this framework, the research of a growth method of h-BN that is scalable and suitable for integration with graphene and TMDs heterostructures is very active[3].

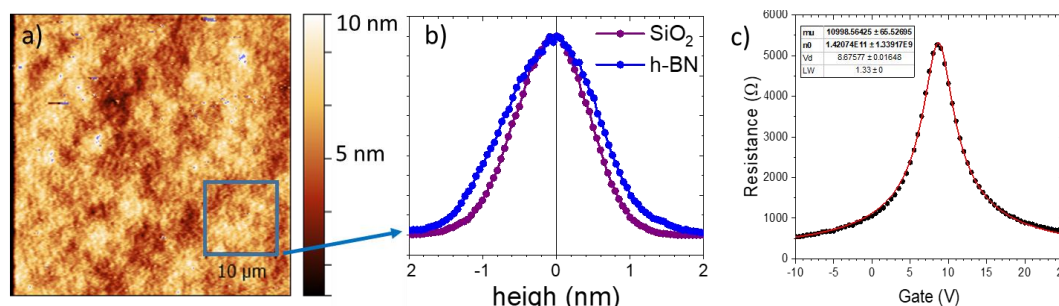
Here we present the realization of graphene/h-BN heterostructures with scalable techniques. h-BN continuous films were grown by Ion Beam Assisted Deposition (IBAD)[4] directly on Si/SiO<sub>2</sub> substrate. Atomic force microscopy (AFM) analysis reveals the atomic flatness of the material (Fig. 1a and 1b). High-quality graphene single-crystal arrays were grown by CVD[5] on copper and transferred on the target h-BN using a semi-dry approach. Raman spectroscopy reveals a reduction in the graphene strain on h-BN. The residual carrier density is in the range between  $8 \times 10^{10} \text{ cm}^{-2}$  and  $20 \times 10^{10} \text{ cm}^{-2}$ , and carrier mobilities around  $10000 \text{ cm}^2/\text{Vs}$  (Fig. 1c), in ambient condition.

This work represents a first step toward the realization of high-mobility graphene/based scalable devices. The quality of the presented scalable heterostack paves the way to the implementation of high-performing devices in electronics and opto-electronics applications.

### References

- [1] M. Romagnoli *et al.*, *Nat. Rev. Mater.*, vol. 3, no. 10, pp. 392–414, 2018.
- [2] S. Pezzini *et al.*, *2D Mater.* **7** 041003, 2020.
- [3] K. K. Kim *et al.*, *ACS Nano*, vol. 6, no. 10, pp. 8583–8590, 2012.
- [4] R. Torres, I. Caretti, *et al.*, *Carbon.*, vol. 74, pp. 374–378, 2014.
- [5] V. Miseikis *et al.*, *2D Mater.*, vol. 4, no. 2, 2017.

### Figures



**Figure 1:** a) AFM characterization of the pristine h-BN film. b) Height distribution on an area of  $100 \mu\text{m}^2$  on h-BN and on SiO<sub>2</sub>. c) Electrical characterization of the graphene on h-BN performed in ambient condition, with mobility of  $10\,000 \text{ cm}^2/\text{Vs}$  and  $n_0 = 1.5 \times 10^{11} \text{ cm}^{-2}$ .

### Acknowledgments

This project has received funding from the European Union's Horizon 2020 research and innovation programme Graphene Flagship under grant agreement No 881603-GrapheneCore3.